

Notice of References Cited	Application/Control No. 10/615,291	Applicant(s)/Patent Under Reexamination CHOI ET AL.	
	Examiner Jennifer M. Kennedy	Art Unit 2812	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,320,213 B1	11-2001	Kirlin et al.	257/295
	B	US-6,809,000 B2	10-2004	Nakao et al.	438/393
	C	US-6,642,100 B2	11-2003	Yang et al.	438/253
	D	US-6,359,295 B2	03-2002	Lee et al.	257/295
	E	US-6,358,794 B1	03-2002	Oh, Ki-Young	438/253
	F	US-2001/0035550	11-2001	Yamazaki et al.	257/306
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	EP000472135A1	02-1996	EPO	Yasaitis et al.	HO1L 29/92
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Wolf et al. Silicon Processing for the VLSI Era, Volume 1- Process Technology, Second Edition, Lattice Press 2000, pages 21 219.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

J. Kennedy 11/14/04
Part of Paper No. 20041114